C-RW Series

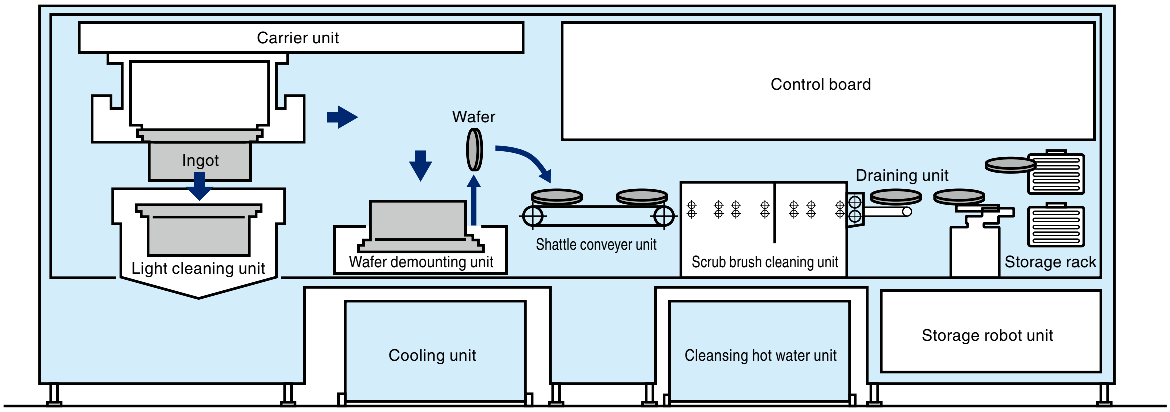
Wafer Demounting & Cleaning Machine

This multifunction wafer demounting and cleaning machine automatically conducts processes from light cleaning, wafer demounting and scrub cleaning of ingots sliced by wire saw to storage into cassettes.

- Designed to be compatible with gluing plates of all wire saw makers
  Sliced ingots can be transferred by ingot lifters built specifically for wire saws
- Handles from water-based slurry to oil-based slurry,and cleaning solutions can be used and recycled through filters
- High throughput
- Makes low running costs possible

TOKYO SEIMITSU CO., LTD.

C-RW-345/C-RW-245




Light cleaning unit


Wafer demounting unit


Conveyor unit


Scrub brush cleaning unit


Cassette storage unit

Basic Specifications

Dimensions,Weight	*Height of indicator light
C-RW-245	5100(W) x 1450(D) x 2200(H) / 2800*mm, 5000kg
C-RW-345	7100(W) x 1650(D) x 2400(H) / 3000*mm, 7000kg
Applicable workpieces	
Ingot slice size	C-RW-245 : 8"(203mm), L(max) = 450mm
	C-RW-345 : 12"(304mm), L(max) = 450mm
Multi-slicing capabilities	2 ingots
Assorted materials	SUS304
Housing frame material	Aluminum extrusion material
Utility	
Cleaning solution	Water for industrial use or Clean-thru : KS-1000
Air supply	At least 0.5MPa
Power supply	200 VAC
Exhaust ventilation	VP200
Drain and exhaust port	50A
Automation	
Host computer signals	SECS-1/2compliant, HSMS or RS232C connection possible
Signal tower	3-color indicator

Structural Specifications

Slide ingot carrier unit	
Slide unit & hand unit	Chuck with vertical 180° inversion mechanism
Light cleaning unit and light cleaning lifter	Oscillating control on a light cleaning lifter
Light cleaning (sliced cleaning)	
Structure	Chamber structure
Cleaning	Splay nozzle showering
	Oscillating control and shower cleaning
Wafer demounting	
Structure	Demounting tank + Wafering unit + Lot partition
Demounting	Demounting tank max. temperature : 95˚C
Conveyor unit	
Structure	Shuttle conveyor
Carrier	Max.speed : 80mm/sec
Scrub cleaning unit	
Structure	Cleaning tank (Brush cleaning,rinse tank) + drying
Cleaning	Front and back reversble brush + Cleaning water nozzle
Supply unit/Storage unit	
Structure	Wafer carrier robot + carrier set
Storage carrier	Cassette carrier type(4C/8C/12C:25cassettes per carrier)

ACCRETECH

Japan / Head Office Tokyo Seimitsu Co., Ltd.
2968-2, Ishikawa-machi, Hachioji-shi, Tokyo,192-8515 Japan
TEL：(042) 642-1701 FAX：(042) 642-1798
https://www.accretech.com/en/

Contact information